

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings of claims in the application:

**Listing of Claims:**

1. (Currently Amended) A sensor comprising:  
a substrate bearing a first electrode coplanar with a second electrode; and  
a dielectric seismic mass overlying and separated from the electrodes by a gap,  
wherein movement of the seismic mass parallel to the electrode plane alters a rate of occupation of space by the dielectric material in a fringe electric field arising between the electrodes.
2. (Original) The sensor of claim 1 wherein the first and second electrodes are comb-shaped.
3. (Original) The sensor of claim 1 wherein the dielectric seismic mass comprises Parylene.
4. (Original) The sensor of claim 1 wherein the seismic mass is perforated by holes.
5. (Canceled)
6. (Currently Amended) The sensor of claim ~~[[5]]~~ 13 wherein movement of the seismic mass normal to the electrode plane alters the rate of occupation of space by the dielectric material.
7. (Canceled)
8. (Currently Amended) The sensor of claim ~~[[7]]~~ 1 further comprising a third electrode separated from a fourth electrode on the substrate, wherein seismic mass defines a first hole between the first and second electrodes, and a second hole between the third and fourth electrodes, the second hole offset in pitch from the first hole.

9. (Original) The sensor of claim 1 further comprising a beam in contact with an anchor portion and configured to support the dielectric mass over the electrodes.

10. (Original) The sensor of claim 9 wherein the beam exhibits a linear shape.

11. (Canceled)

12. (Original) The sensor of claim 9 wherein the beam is configured to accommodate movement of the seismic mass parallel to the electrode plane.

13. (Currently Amended) ~~The sensor of claim 9~~ A sensor comprising:  
a substrate bearing a first electrode coplanar with a second electrode;  
a dielectric seismic mass overlying and separated from the electrodes by a gap;  
and  
a beam in contact with an anchor portion and configured to support the dielectric mass over the electrodes, wherein the beam exhibits a spiral shape.

14. (Original) The sensor of claim 1 wherein the dielectric seismic mass and the beam comprise integral features of a dielectric layer.

15-24. (Canceled)